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S/N 10/590067

PATENT

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

SHIMOMURA et al.

Examiner:

ELEY, Timothy V.

Serial No .:

10/590067

Group Art Unit:

3724

Filed:

Docket No.:

08279.1153USWO

Title:

August 21, 2006 POLISHING PAD AND METHOD FOR MANUFACTURE OF

SEMICONDUCTOR DEVICE USING THE SAME

I hereby certify that this paper is being transmitted by facsimile to the U.S. Patent and Trademark Office on March 24,

## <u>AMENDMENT AND RESPONSE</u>

Mail Stop: AMENDMENT Commissioner for Patents P.O. Box 1450 Alexandria, Virginia 22313-1450

Dear Sir:

In response to the Office Action mailed January 23, 2008, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims that begins on page 2 of this paper.

Remarks begin on page 4 of this paper.